

High performance, low dissipation QCL across the mid-IR range

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IQCLSW 2014, Policoro



Outline

- Alpes Lasers overview
- Single mode sources
 - DFB sources below 1W between 4.5-9.3 μ m
 - High power DFB
- High power FP devices
- Conclusion and next steps

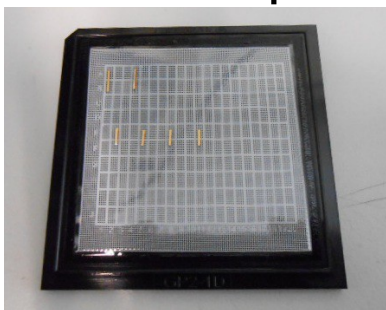


Our company

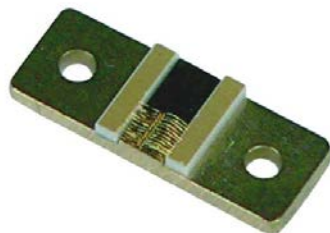
Alpes Lasers

- founded in 1998
- 19 employees (11PhD, 5 eng.)
- >200 Person*Year
- fabless component manufacturer
- 2400+ sold lasers
- 550+ packaged lasers
- several patents on QCL principles

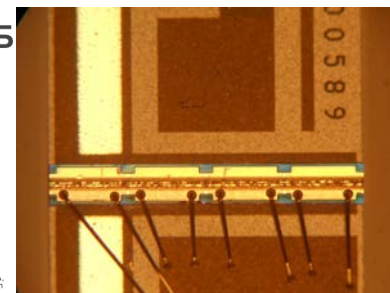
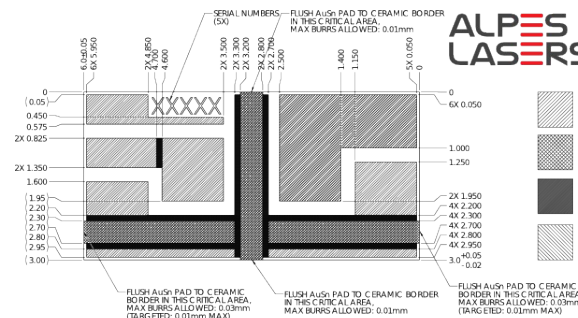
■ Bare chips



■ NS



■ AlN submount (3x6mm)



■ TC3



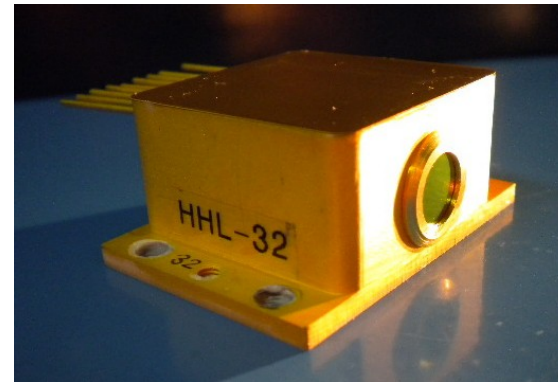
■ Driver kits (starter kits)



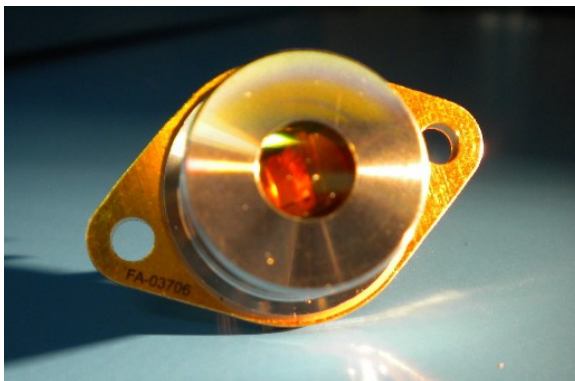
■ TO3-L



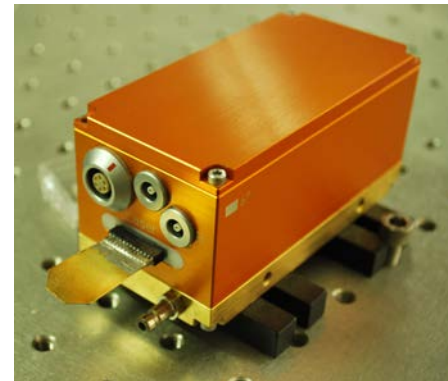
■ HHL-L



■ TO3-W

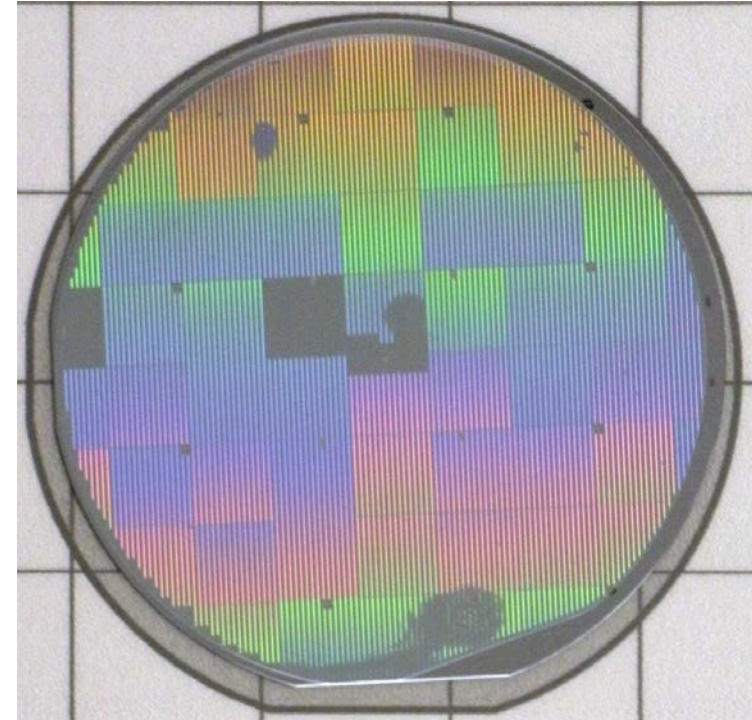


■ LLH



■ lower consumption packages being validated (TO5, etc.)

UV technology



DFB grating during fabrication

		C7 1.9655 0.8%	D7 1.9145 1.6%	E7 1.8085 2.0%	F7 1.9255 1.6%	G7 1.8765 0.8%		
	B6 1.836 1.2%	C6 1.948 2.0%	D6 1.8645 2.0%	E6 1.8765 2.0%	F6 1.7765 2.0%	G6 1.8695 2.0%	H6 1.933 1.2%	
A5 1.887 0.4%	B5 1.741 2.0%	C5 1.7375 2.0%	D5 1.741 2.0%	E5 1.8835 2.0%	F5 1.734 2.0%	G5 1.746 2.0%	H5 1.887 2.0%	I5 1.7765 0.4%
A4 (LOCK) 00.00000 1.0%	B4 1.8395 2.0%	C4 1.8835 2.0%	D4 (LOCK) 00.00000 2.0%	E4 1.848 1.5%	F4 1.9555 2.0%	G4 1.8765 2.0%	H4 1.873 2.0%	I4 1.7375 1.0%
A3 1.831 1.0%	B3 1.789 2.0%	C3 1.873 2.0%	D3 1.88 2.0%	E3 1.7375 1.5%	F3 1.7565 2.0%	G3 1.887 2.0%	H3 1.799 2.0%	I3 1.843 1.0%
A2 1.746 0.5%	B2 1.9045 2.0%	C2 1.843 2.0%	D2 1.892 2.0%	E2 1.751 2.0%	F2 1.836 2.0%	G2 1.8395 2.0%	H2 1.7615 2.0%	I2 1.9655 0.5%
	B1 1.8695 1.4%	C1 1.9405 2.0%	D1 1.897 2.0%	E1 1.8185 2.0%	F1 1.88 2.0%	G1 1.8595 2.0%	H1 1.826 1.4%	
		C0 1.8545 1.1%	D0 1.724 1.9%	E0 1.729 2.0%	F0 1.7665 1.9%	G0 1.734 1.1%		

Proprietary gratings design tool

- gratings written by standard lithography from 4-12 μm
- many different wavelengths can be fabricated at once
- efficient device mounting
- full 2"-wafer process
- polyvalent production process

Single mode sources

A killer application is still missing... why ?

- Laser sources :
 - Low efficiency compared to diode lasers
 - High electrical dissipation ($W_{el} \gg 1W$)
 - Nb of lasers per wafers still low (long lasers & small wafers)
 - Fabrication is still expensive
- Photonics :
 - Difficult to do photonic integration
 - Optical elements expensive
 - Detectors less sensitive and more expensive

- Most of QCLs have 5-15 W of electrical dissipation
- Up to 100 W are needed to control the temperature
- Optical power levels of few mW sufficient for many applications

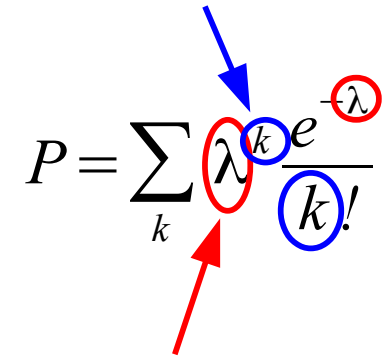
- Most of QCLs have 5-15 W of electrical dissipation
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- Optical power levels of few mW sufficient for many applications

Research goal:

- Low dissipation devices
- Short chips
- Still enough optical power for spectroscopy

- Low dissipation (more easy CW bar testing)
- More devices per wafer

Number of defects



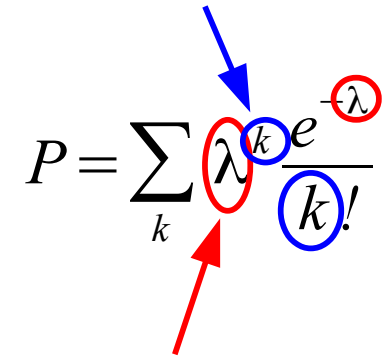
The diagram shows the Poisson distribution formula $P = \sum_k \frac{\lambda^k e^{-\lambda}}{k!}$. A blue arrow points from the text 'Number of defects' to the variable k in the exponent of the summation. A red arrow points from the text 'Probability of major defect in the laser wg' to the variable λ in the numerator of the fraction.

$$P = \sum_k \frac{\lambda^k e^{-\lambda}}{k!}$$

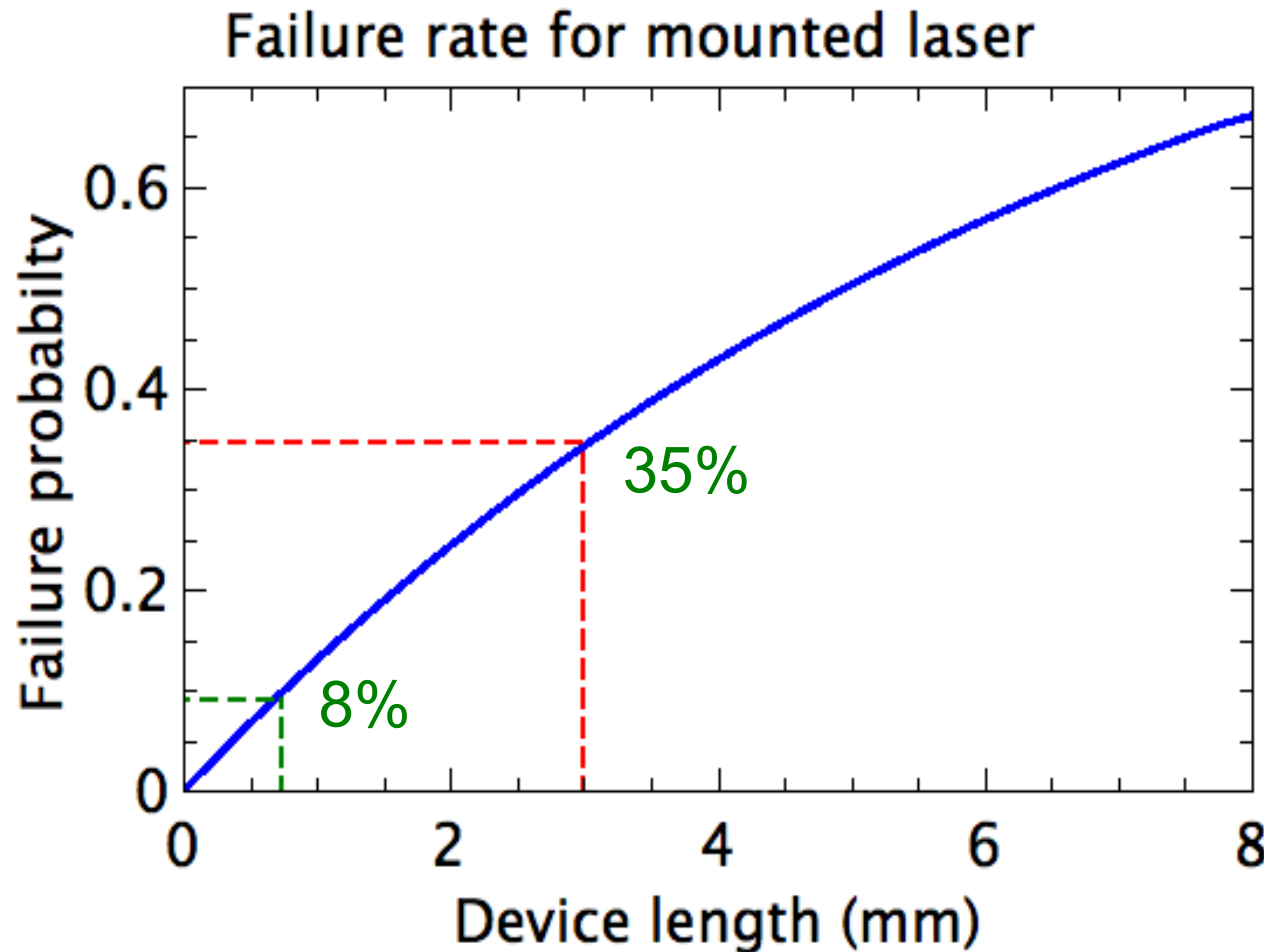
Probability
of major defect
in the laser wg

- Low dissipation (more easy CW bar testing)
- More devices per wafer
- Probability of defects (λ) follows a Poissonian law
- Failure rate sensibly reduced with shorter lasers

Number of defects

$$P = \sum_k \lambda^k \frac{e^{-\lambda}}{k!}$$


Probability
of major defect
in the laser wg

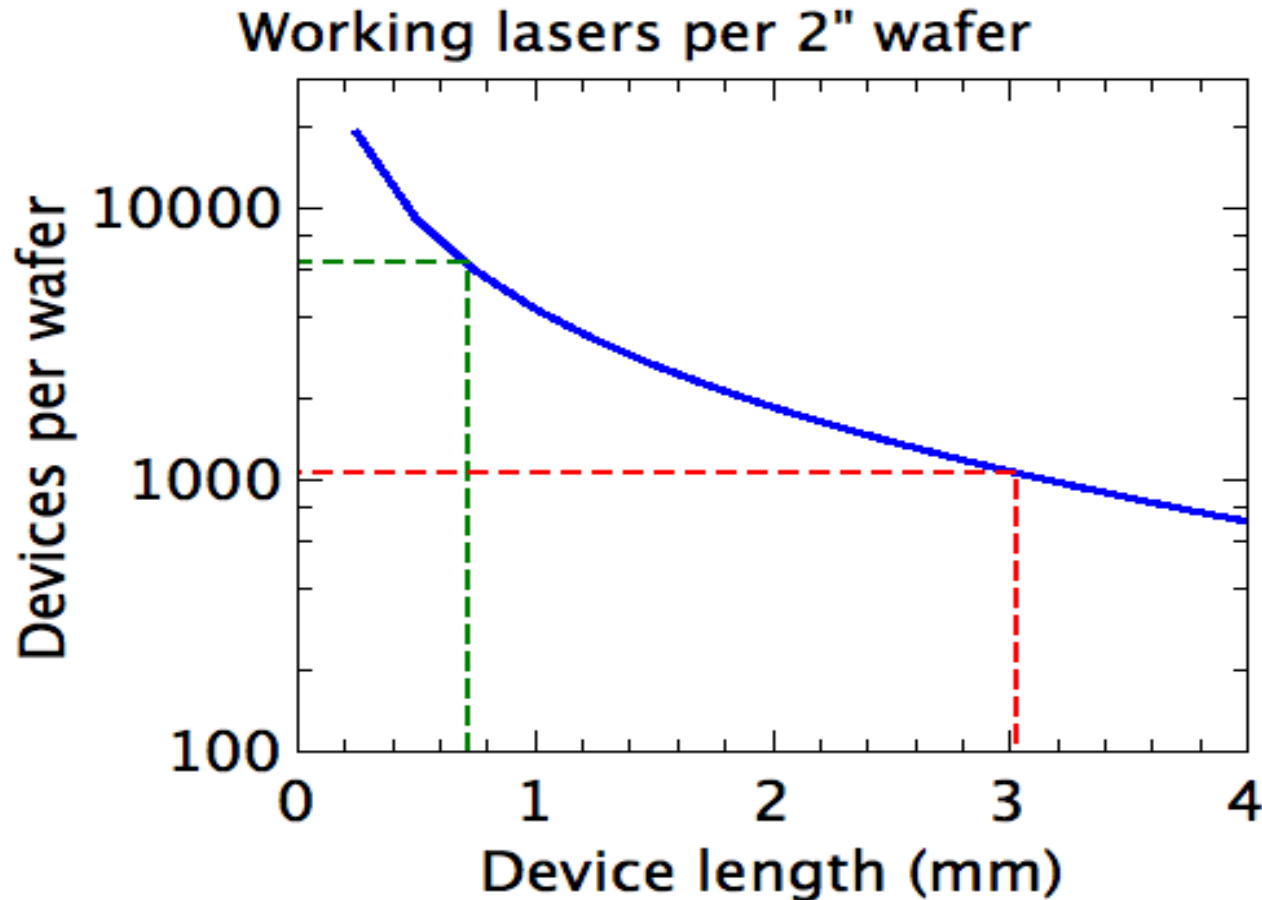


Number of defects

$$P = \sum_k \lambda^k \frac{e^{-\lambda}}{k!}$$

Probability of major defect in the laser wg

- Defect density estimated on the AL-Stock data (preliminary)



Number of defects

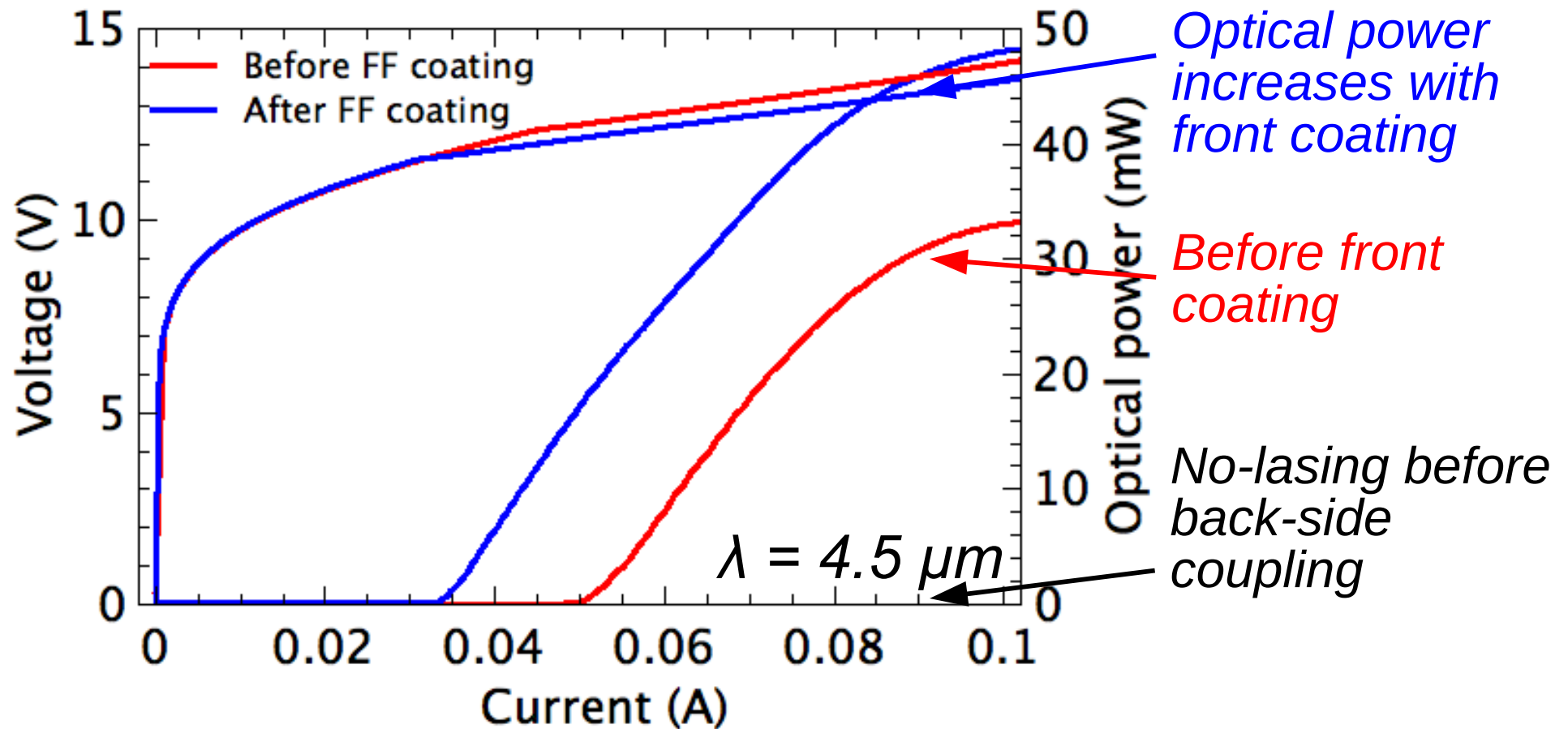
$$P = \sum_k \frac{\lambda^k e^{-\lambda}}{k!}$$

Probability
of major defect
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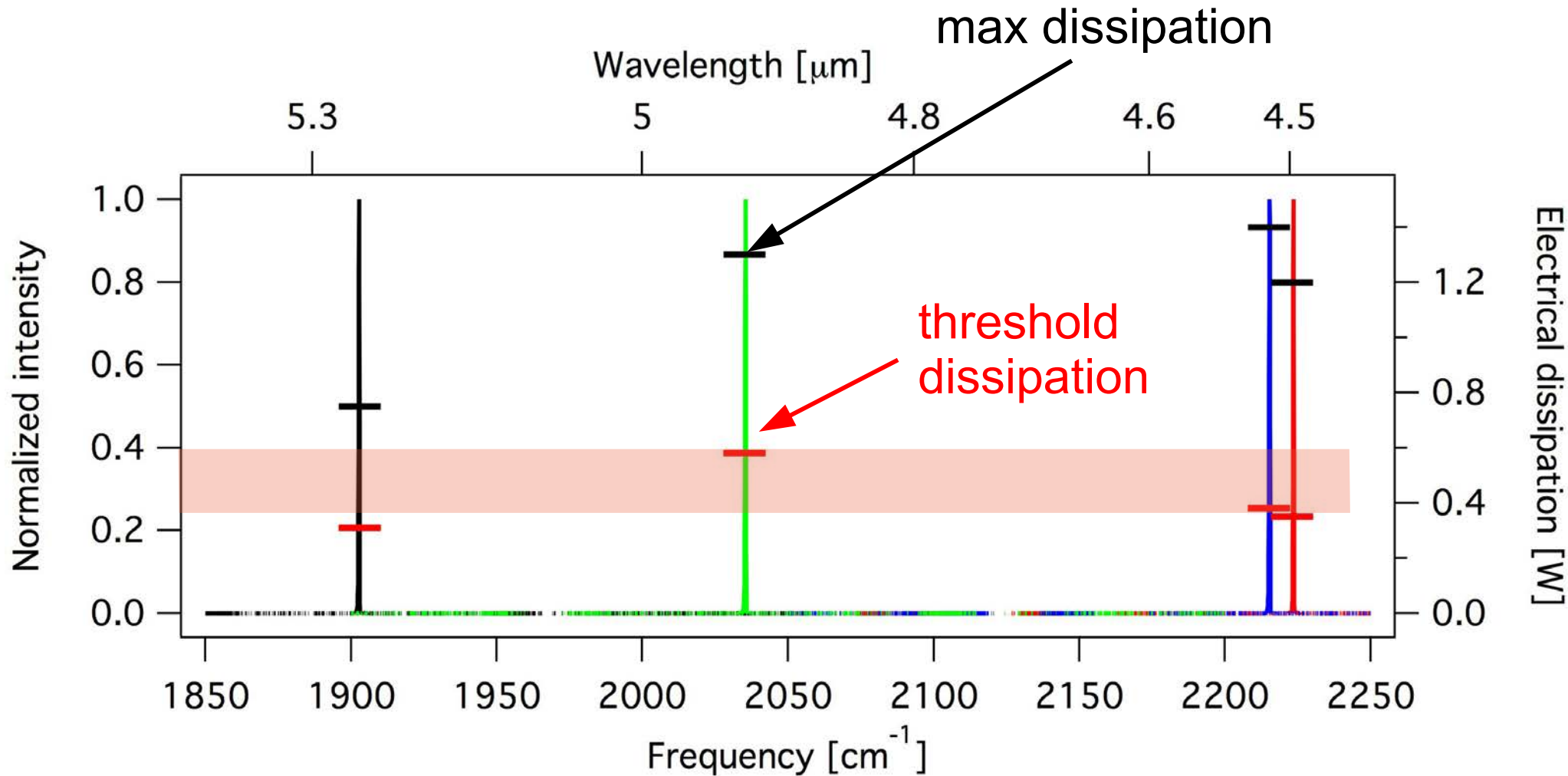
- Doublefold impact on the number of chips/wafer

- Starting range 4.5 μm and 5.5 μm
- Optimize the grating coupling to obtain both low **consumption DFBs** and **high power DFBs** on the **same wafer**
- 750 μm -long devices, 3-4 μm -wide
- Back-facet HR coating
- Front-facet partial HR coating

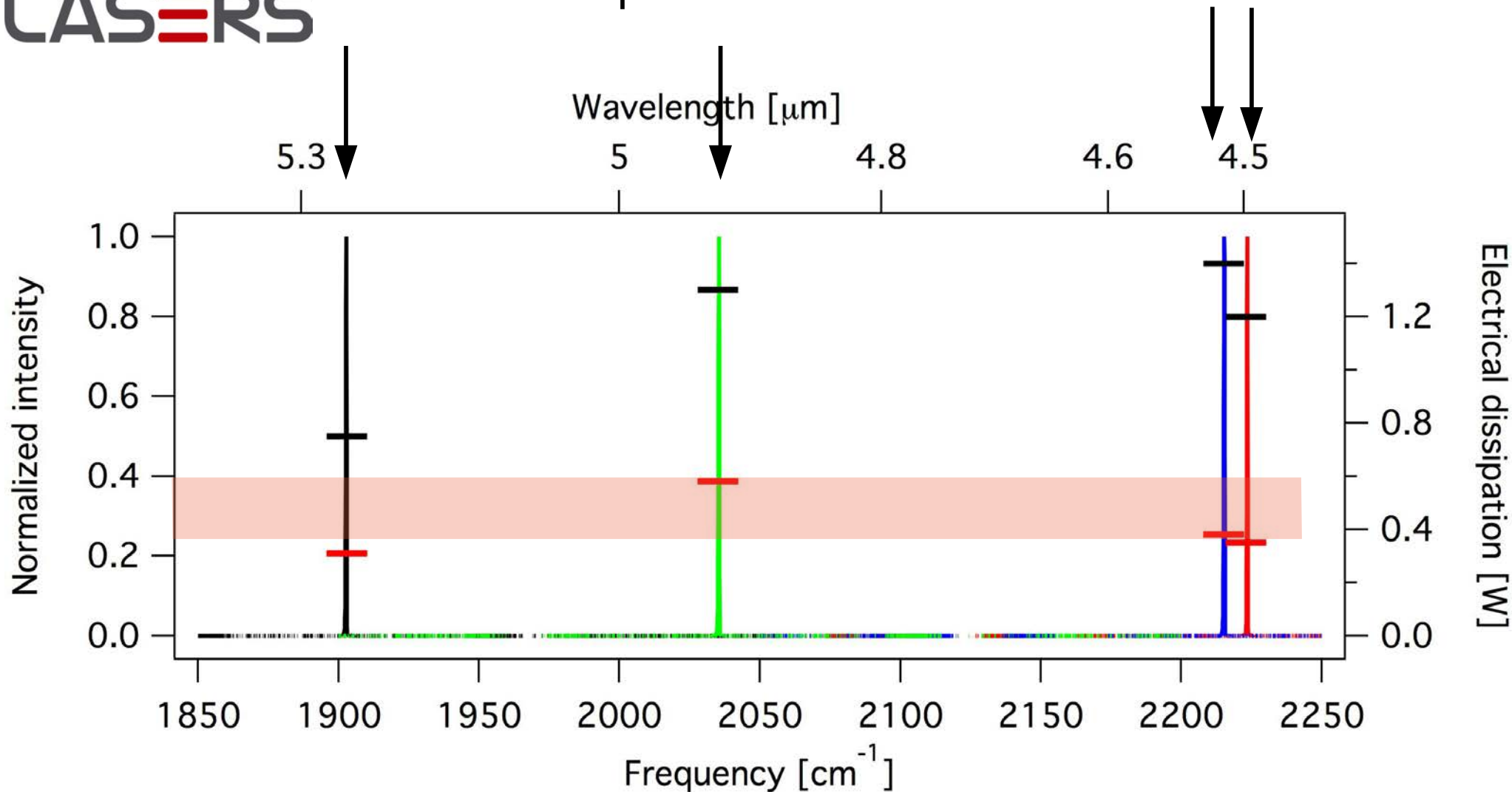
Effect of front-facet coating



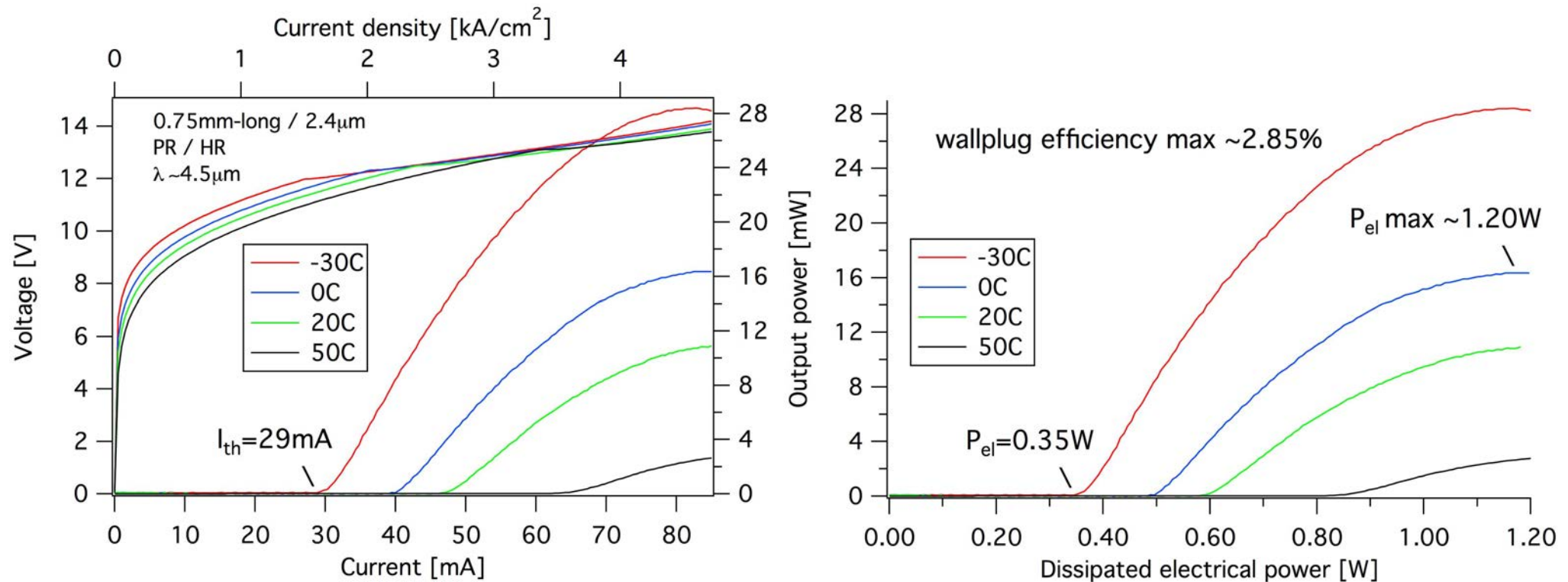
750 μm long devices
3 μm wide ridge



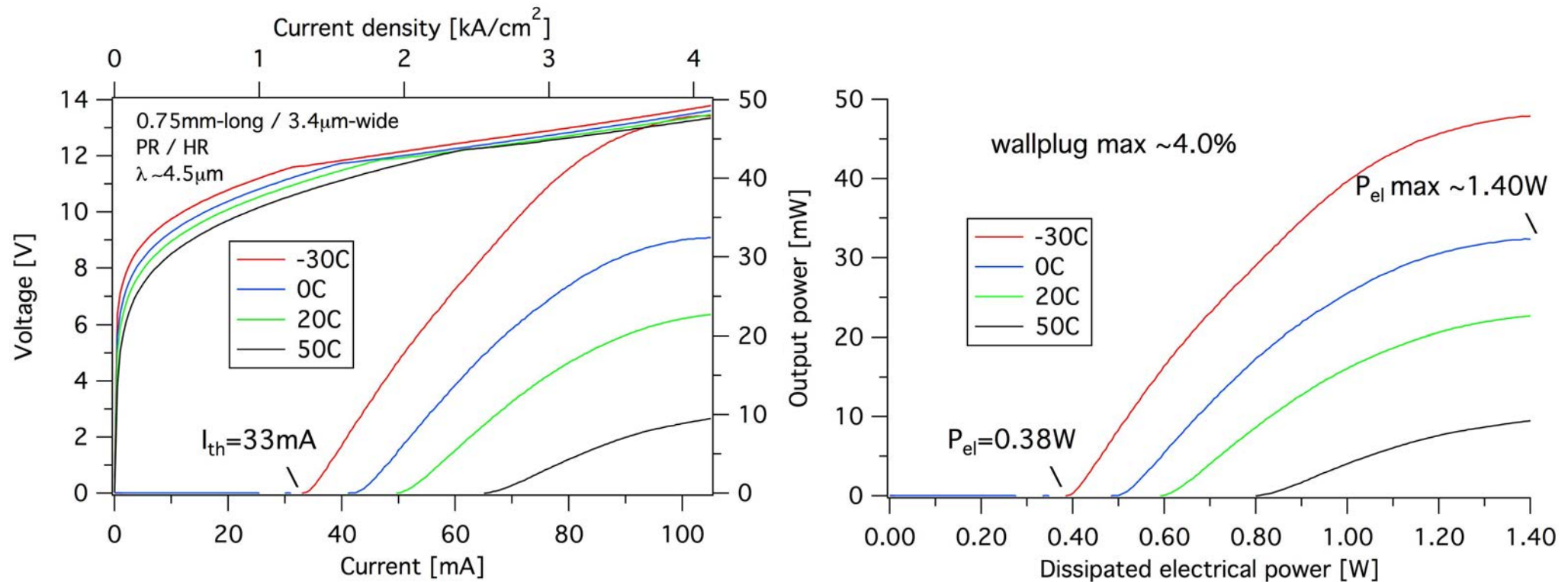
- dissipation at threshold as low as 0.3W
- max consumption < 1.4W between 4.5 μm and 5.3 μm



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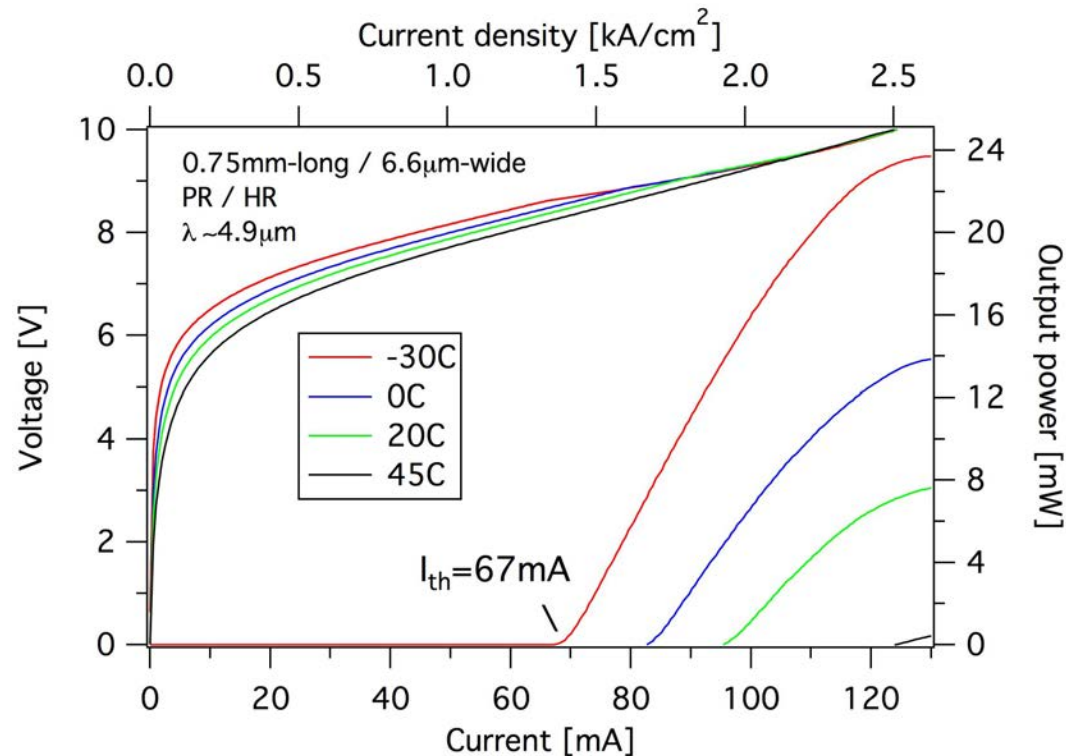


- ♦ very low threshold current : **29mA**
- ♦ P_{el} max $\sim$ **1.2W**
- ♦ single-mode

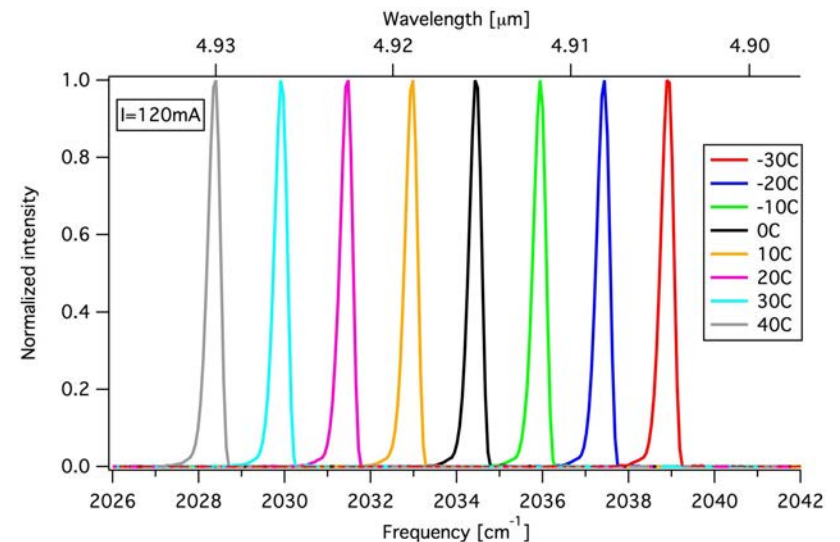
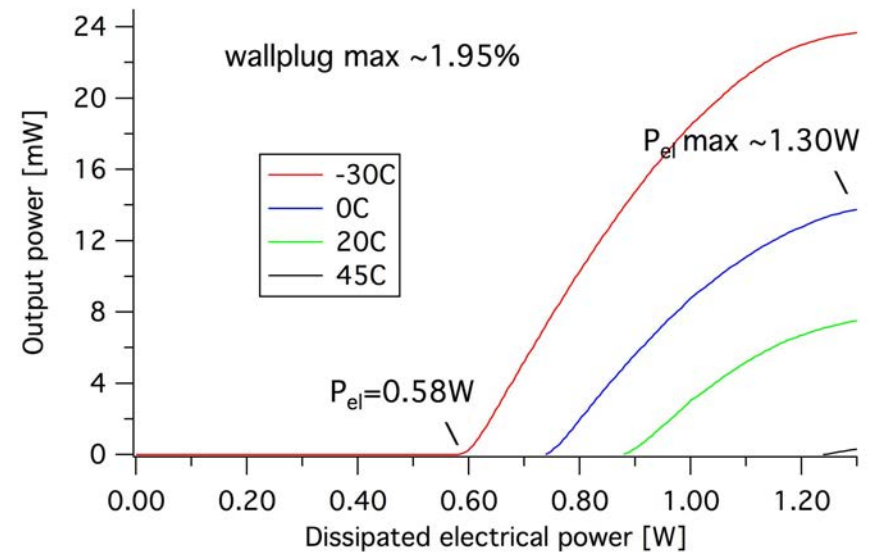


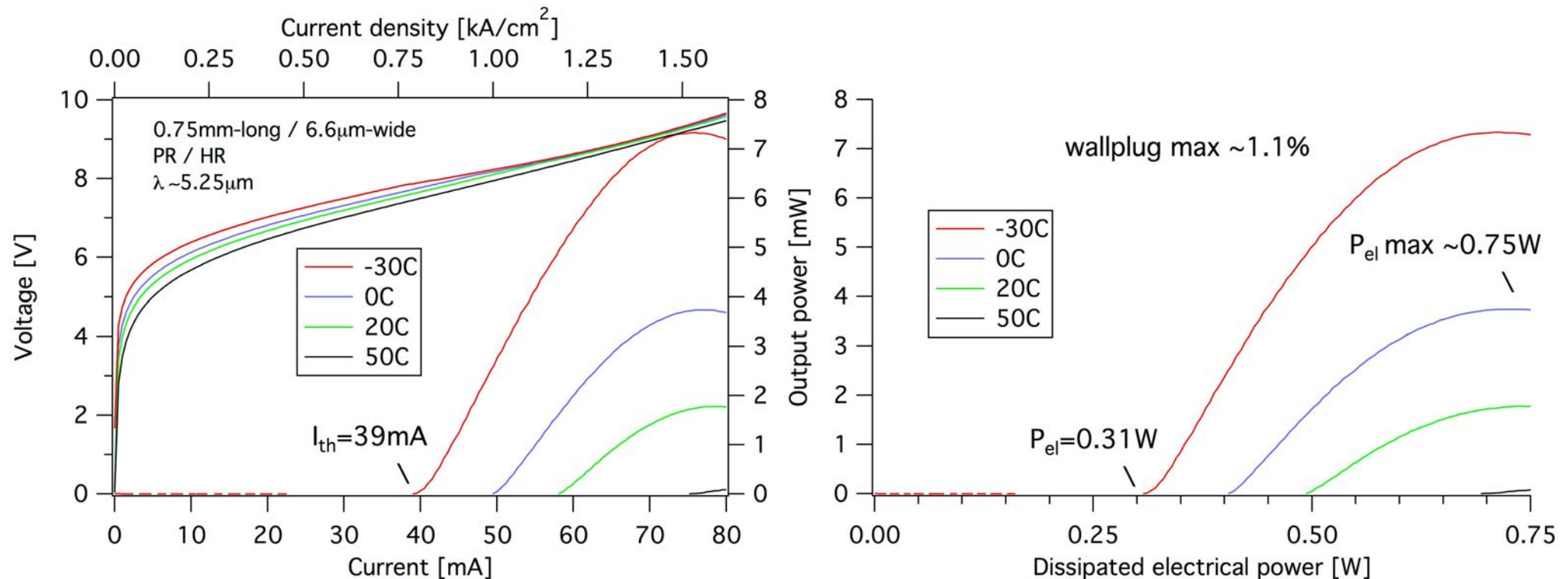
- ♦ opt power up to **48mW** / wallplug up to **4%**
- ♦ P_{el} max $\sim 1.4\text{W}$
- ♦ single-mode

Low-dissipation DFB devices at 4.90 μm

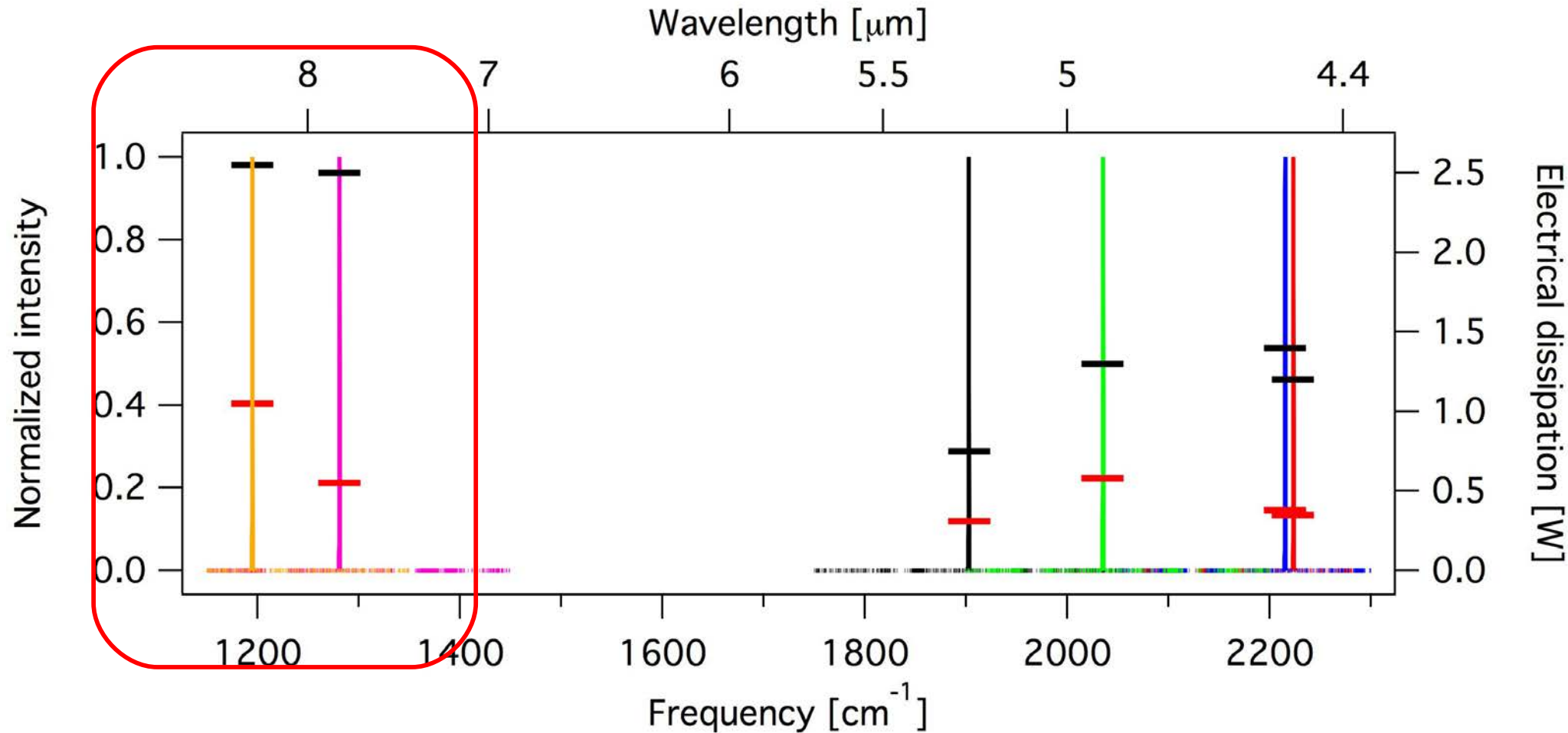


- broader ridges
- low threshold current : 67mA
- $P_{\text{el}} \text{ max} \sim 1.3\text{W}$

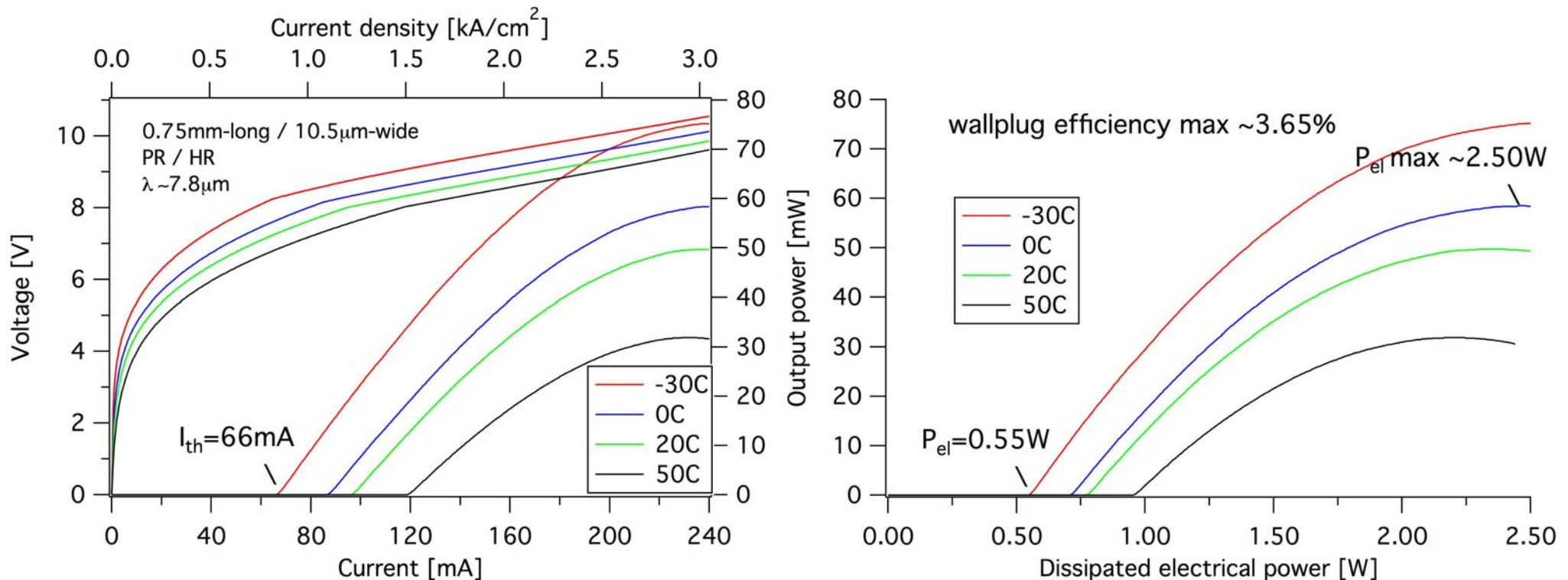




- electrical dissipation as low as **0.31W**
- $P_{el} \text{ max } \sim \mathbf{0.7W}$
- gain starving (too low doped layer)
- single-mode



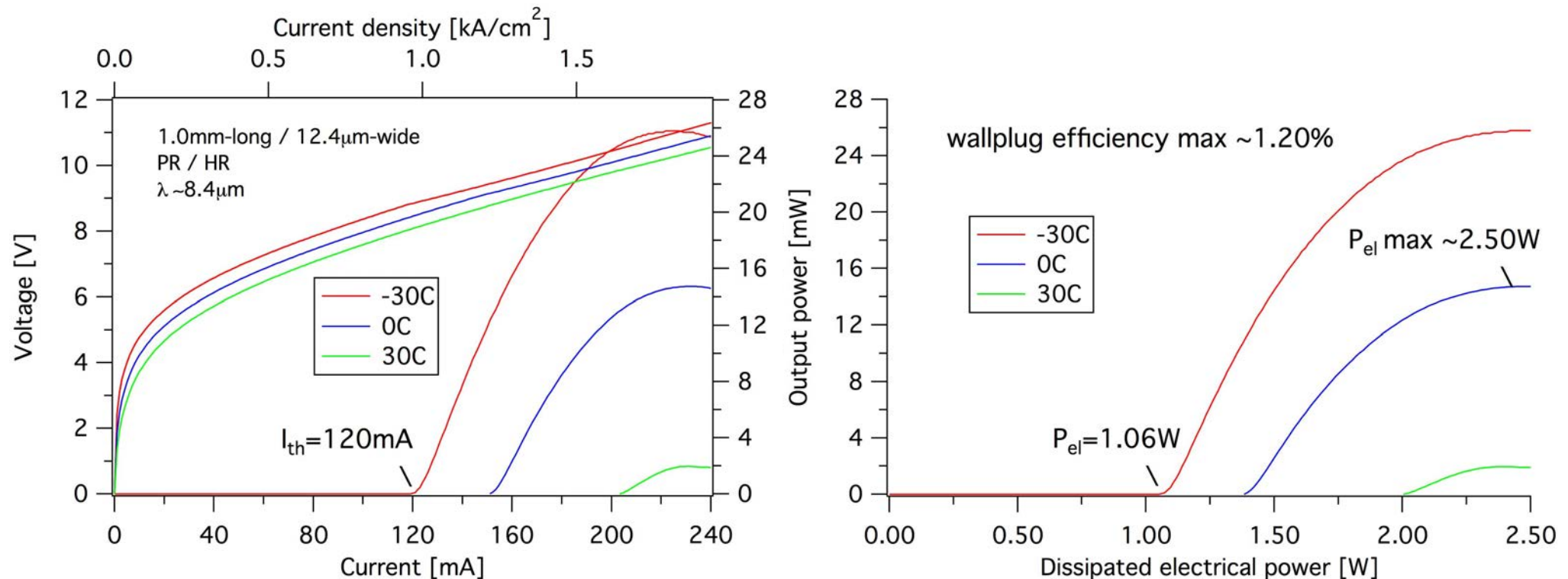
- max consumption < 2.6W between 4.5μm and 8.4μm



- very low threshold current : 66mA
- very low threshold power : **0.55W**
- $P_{max} > 70\text{mW}$ / huge dynamical range
- single-mode

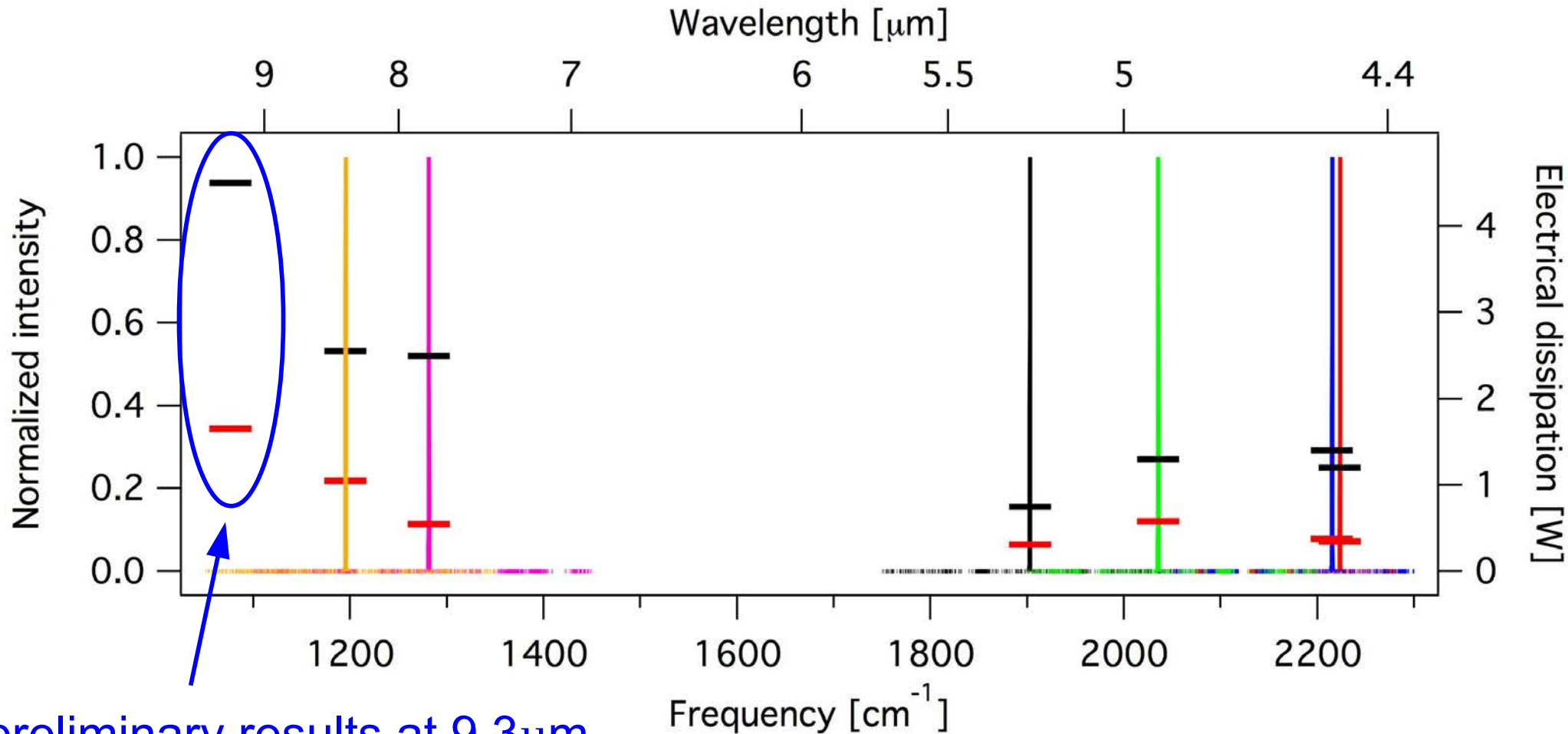
PR coatings:
S. Riedi (ETHZ)

Low-dissipation DFB devices at 8.4 μm

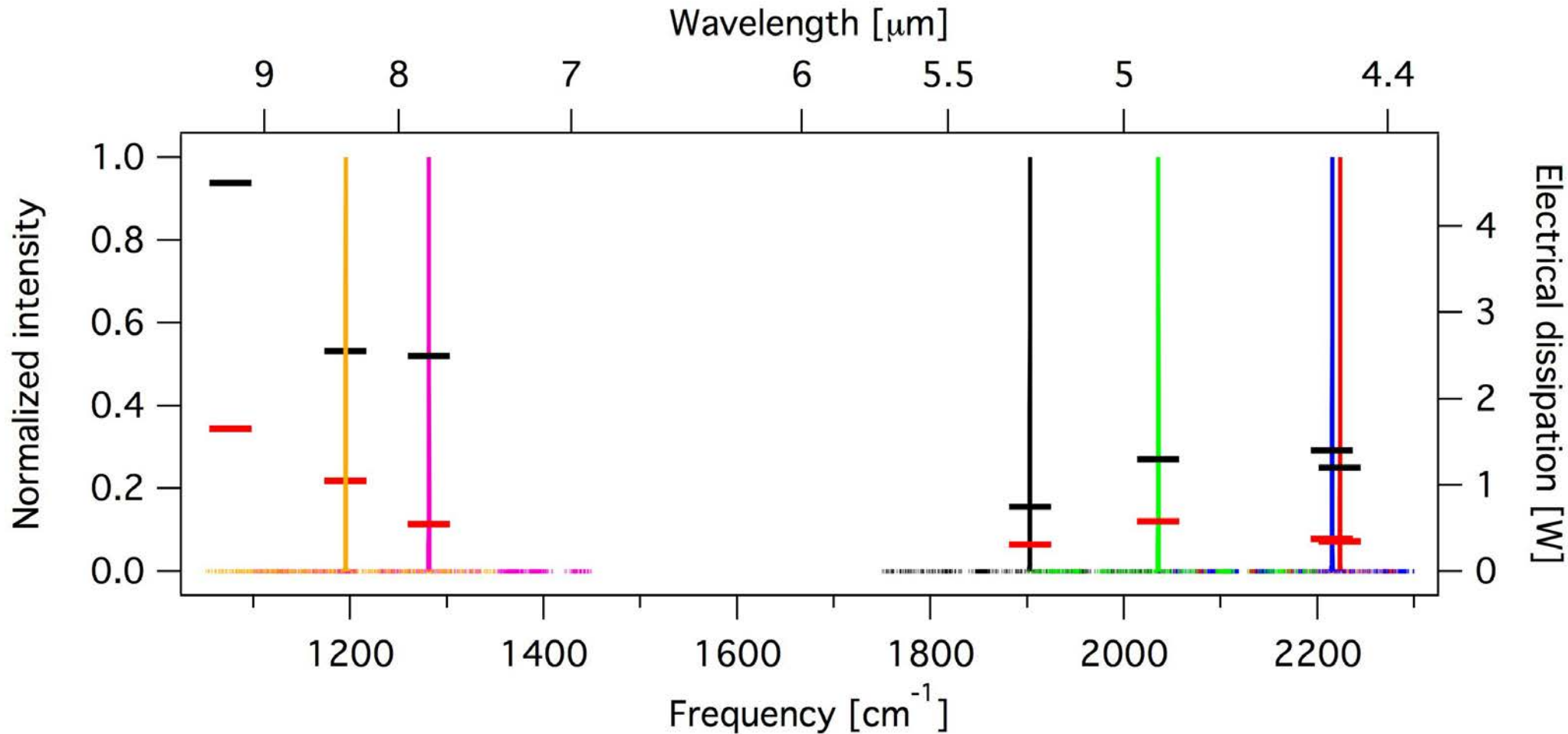


- did not lase while uncoated/HR !
- low threshold power : 1.06W
- single-mode
- as for 4.9 μm case, design is too little doped

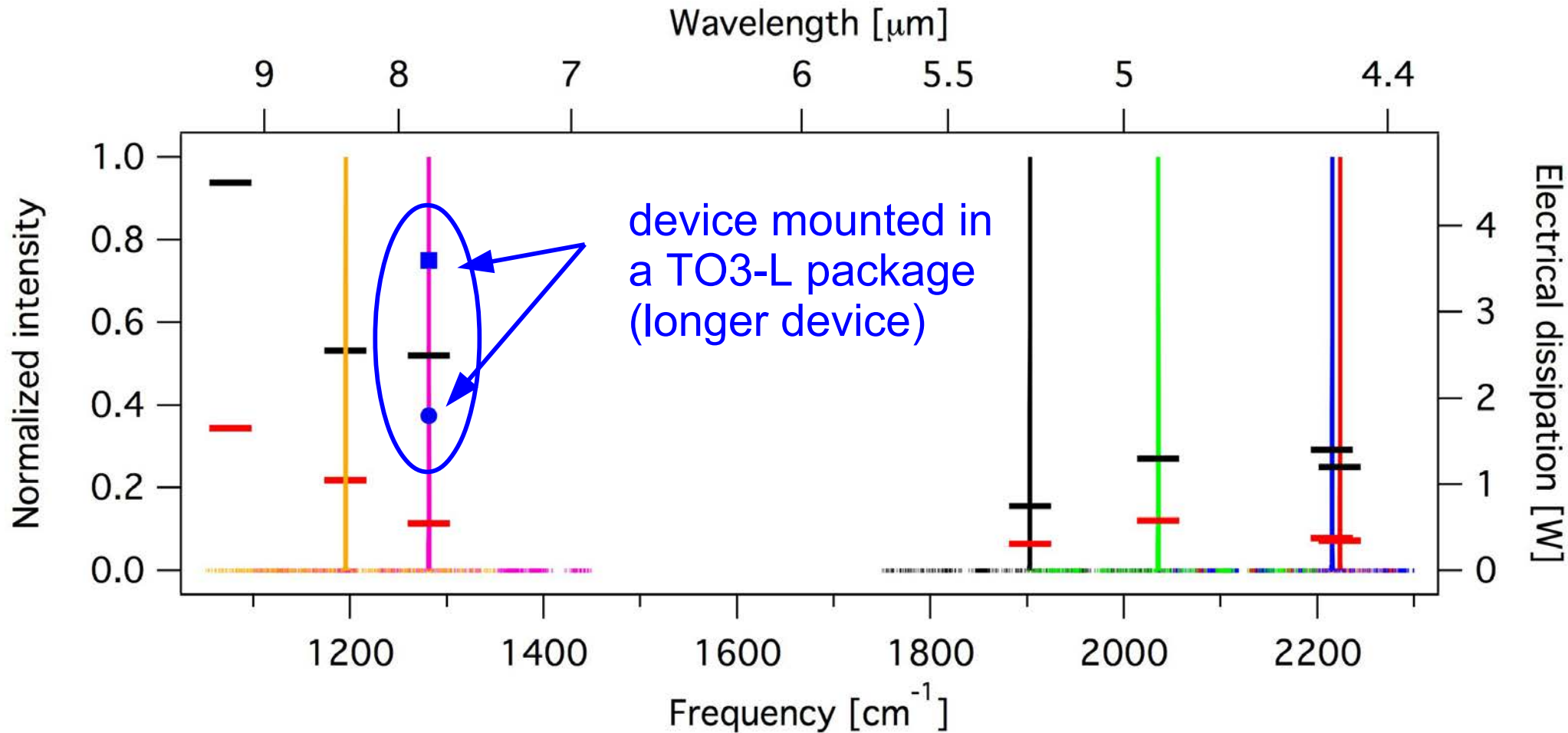
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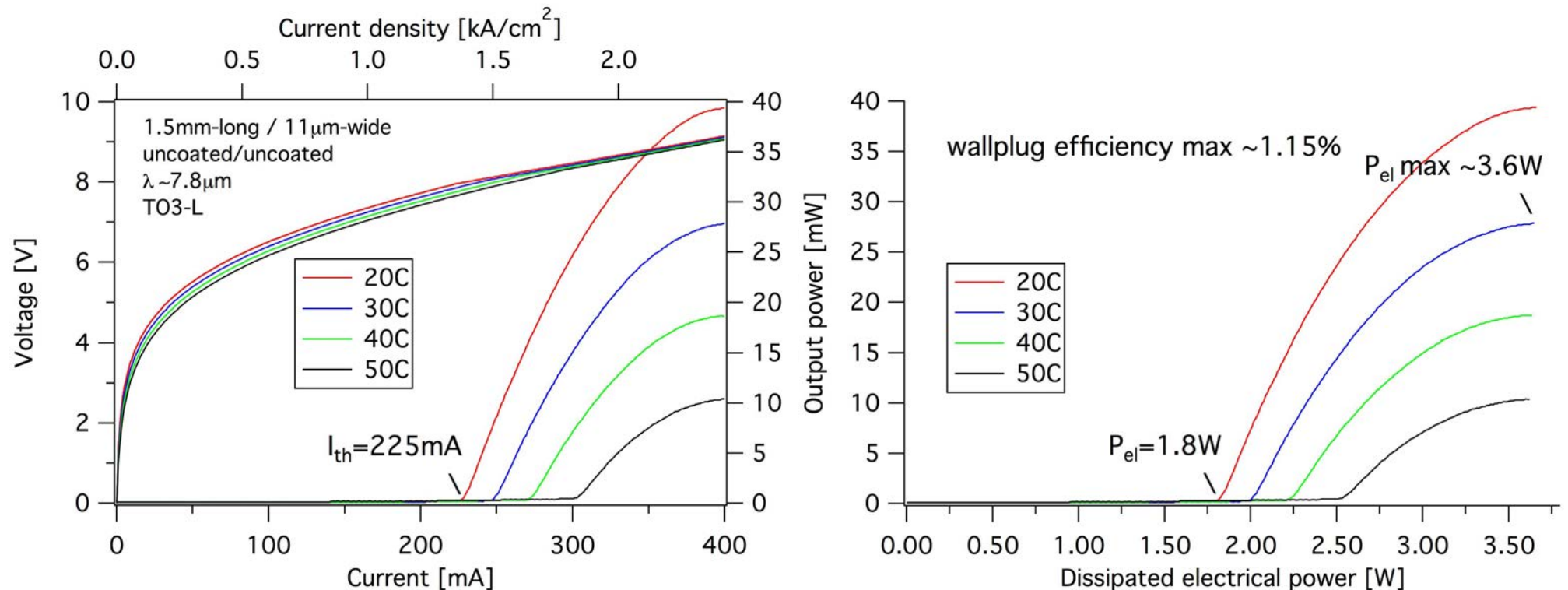
preliminary results at 9.3 μm
(only HR on back facet)
FF coating not yet implemented



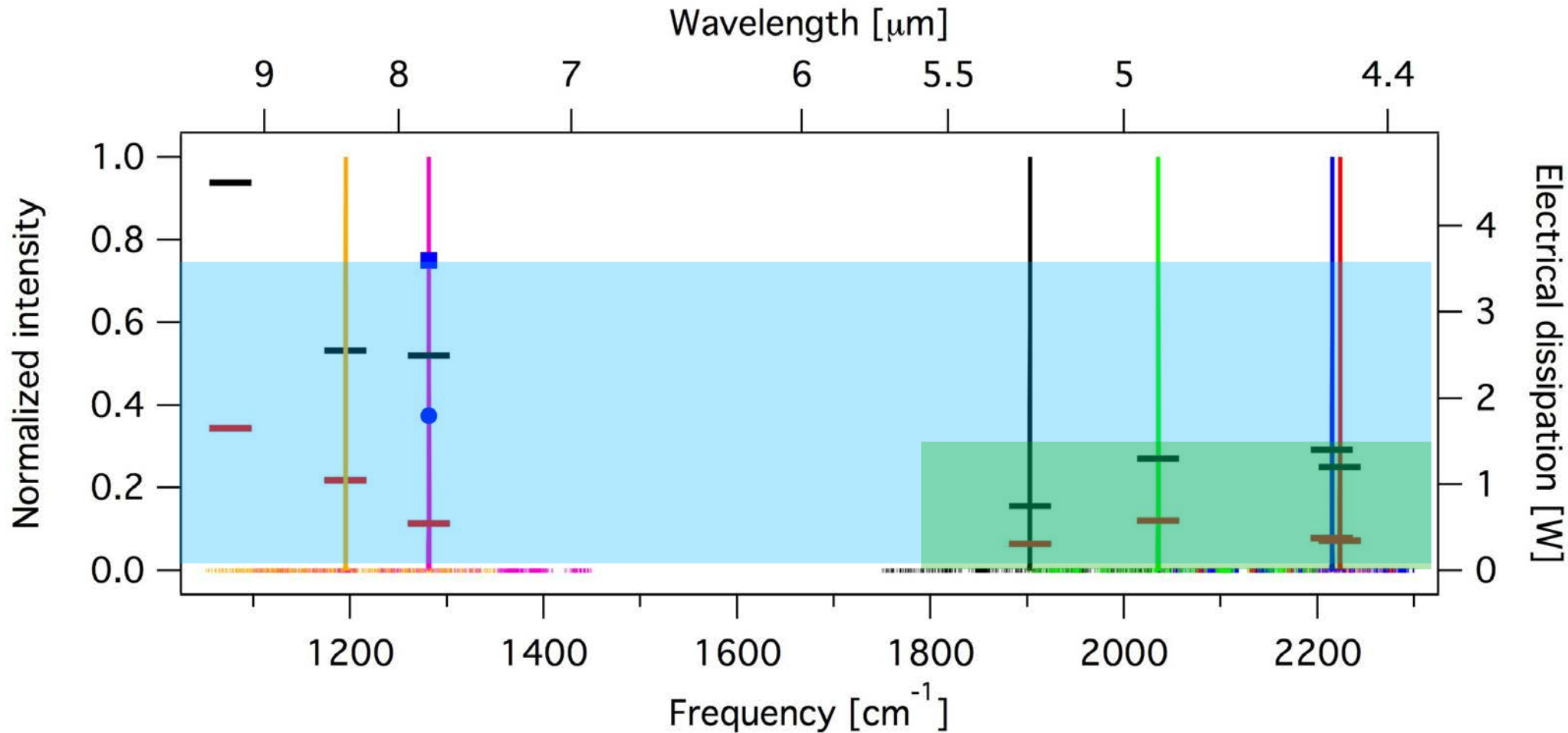
Can we package these devices in low-dissipation packages ?



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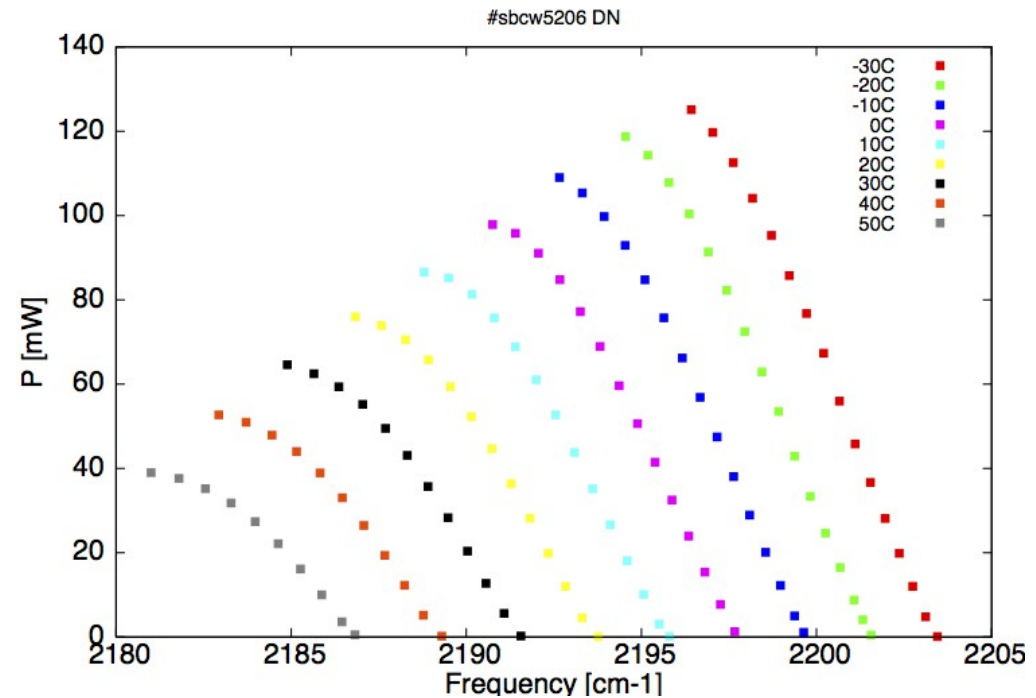
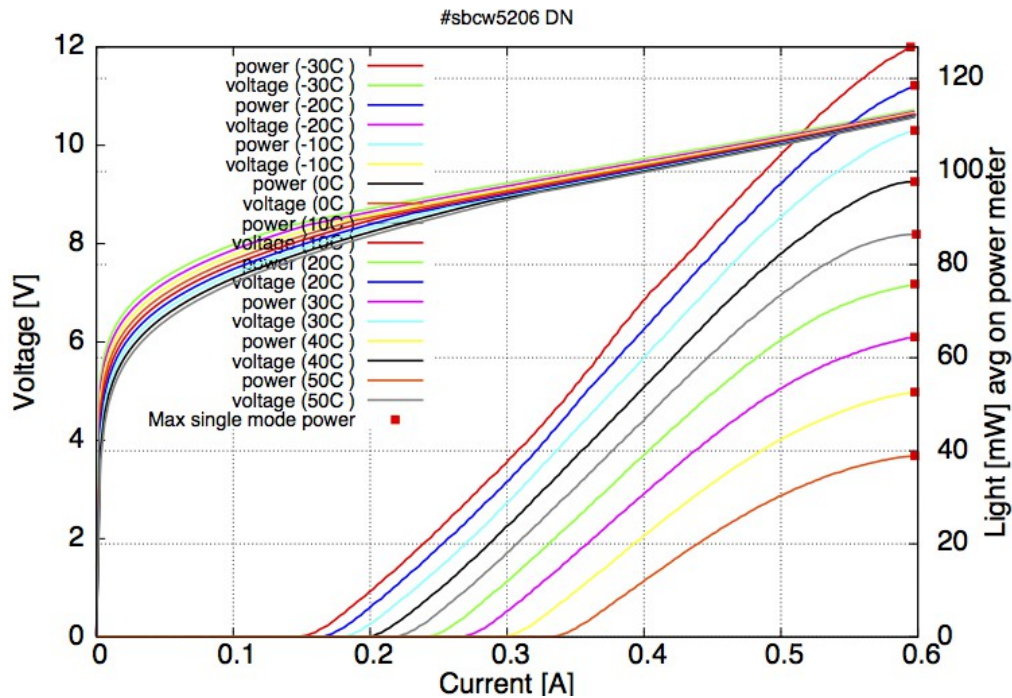


- longer / uncoated device !
- higher currents but CW operation in TO3-L
- max electrical power : up to 3.6W
- single-mode

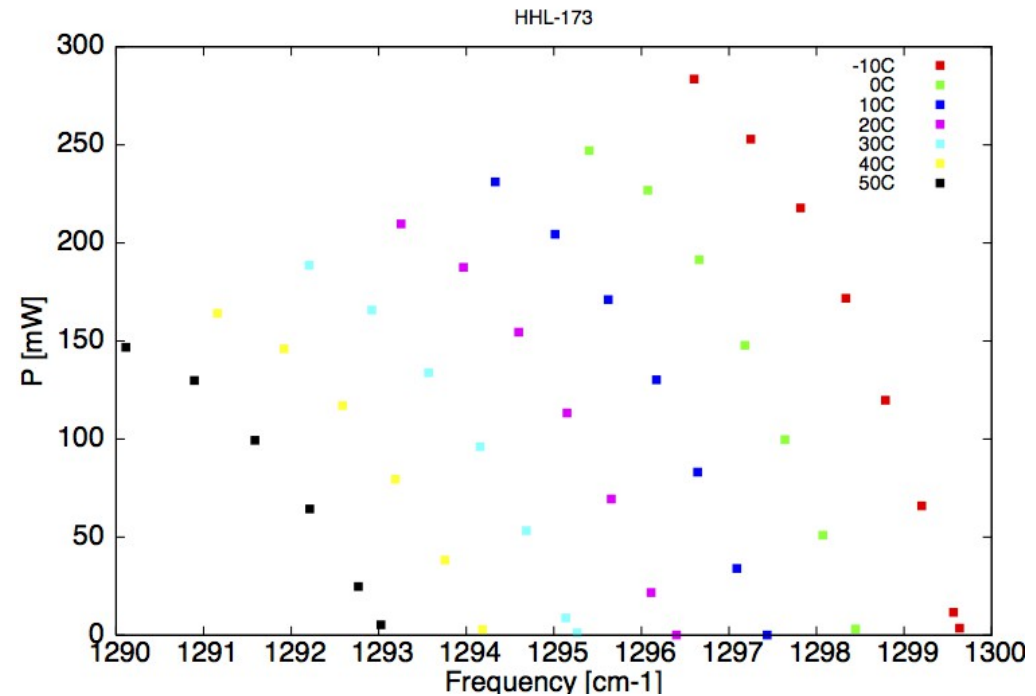
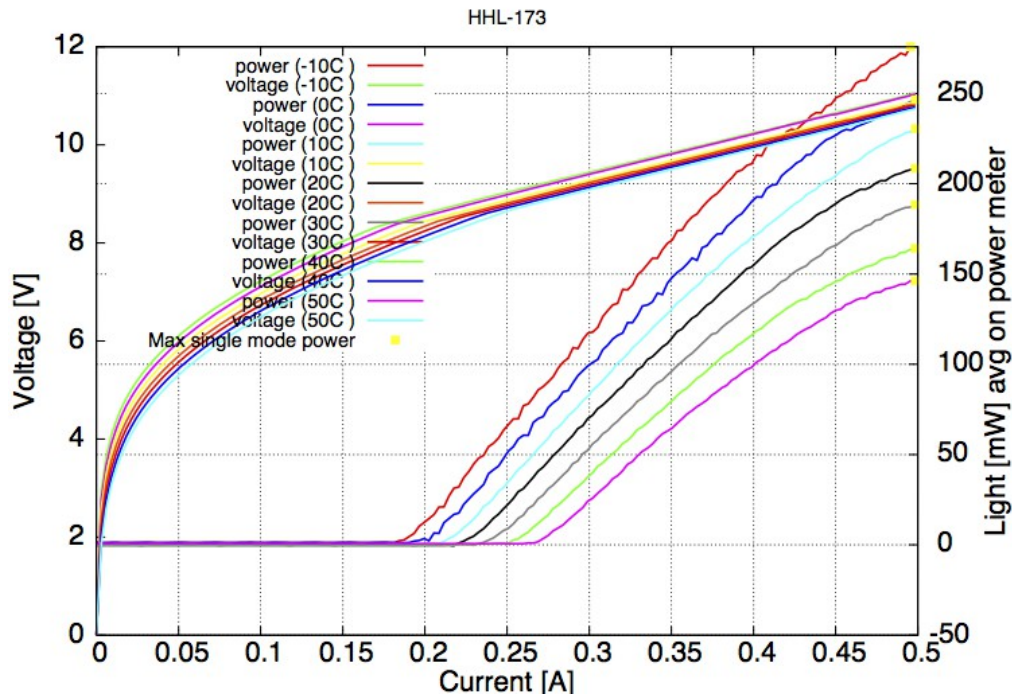


- **blue** : uncoated device in a TO3-L
- all range suitable for TO3 operation !!
- smaller packages for low wavelengths

High power DFB devices at 4.56 μm



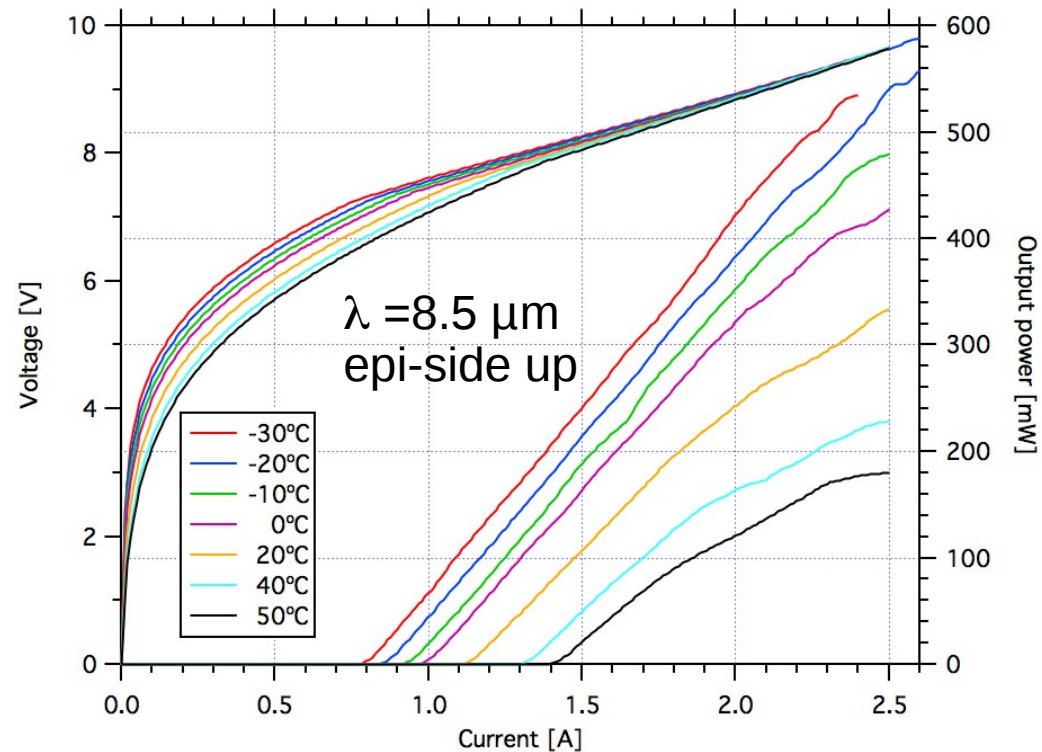
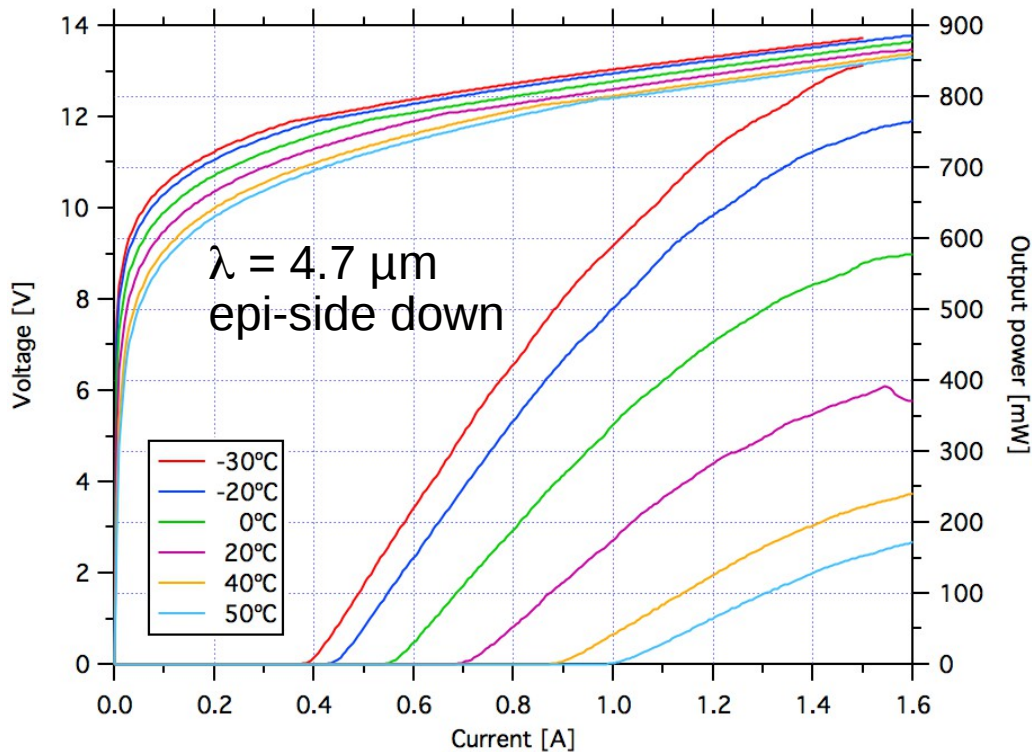
- ~ 80mW at RT / still > 40mW at 50C
- $P_{el} \text{ max} < 6.4\text{W}$
- single-mode across the all range



- ~ 200mW at RT / still **>140mW at 50C**
- P_{el} max < 5.5W
- single-mode across the all range

High-power FP devices

- high power CW operation on TEC
- preliminary results, not yet optimized



- facet coatings : uncoated/HR (no partial AR)

Conclusion

- Low-dissipation DFB lasers between 4.5 and 9.3 μm with T_{op} up to $>50\text{C}$
- High-power DFB using the same fabrication process ($>140\text{mW}$ at 50C)
- Range of available lasers to be expanded
- Broadgain optimisation for CW operation
- High-power devices optimisation
- Genetic optimisation of the active region design to increase efficiency
- Cloud simulation capability

Special thanks to:

- Dr. Alfredo Bismuto (R&D, process)
- Dr. Tobias Gresch (process masks)
- Dr. Richard Maulini (high power)
- Dr. Romain Terrazzi (design, simulations)
- Dr. Pierre-Yves Baroni (coatings)
- all Alpes Lasers team



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